



TSMC-02-1129

December 19, 2003

To: Commissioner for Patents
P.O.Box 1450
Alexandria, VA 22313-1450

Fr: George O. Saile, Reg. No. 19,572
28 Davis Avenue
Poughkeepsie, N.Y. 12603

Subject: | Serial No. 10/666,493 09/19/03 |

Kuo-Tang Hsu et al.

A NOVEL DESIGN TO ELIMINATE WAFER
STICKING

INFORMATION DISCLOSURE STATEMENT

Enclosed is Form PTO-1449, Information Disclosure Citation
In An Application.

The following Patents and/or Publications are submitted to
comply with the duty of disclosure under CFR 1.97-1.99 and
37 CFR 1.56.

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being
deposited with the United States Postal Service as first class
mail in an envelope addressed to: Commissioner for Patents,
P.O. Box 1450, Alexandria, VA 22313-1450, on December 22, 2003.

Stephen B. Ackerman, Reg.# 37761

Signature/Date

 12/22/03

U.S. Patent 6,520,839 to Gonzalez-Martin et al., "Load and Unload Station for Semiconductor Wafers," describes an apparatus for semiconductor manufacturing.

U.S. Patent 6,407,009 to You et al., "Methods of Manufacture of Uniform Spin-On Films," discloses methods to spin-on films for integrated circuits.

U.S. Patent 6,267,853 to Dordi et al., "Electro-Chemical Deposition System," describes an electrochemical deposition system for integrated circuit manufacturing.

The following two U.S. Patents disclose a manufacturing tool for integrated circuit processing:

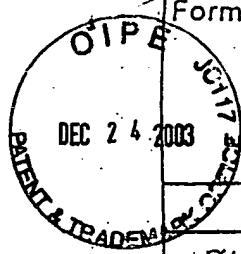
- 1) U.S. Patent 5,950,327 to Peterson et al., "Methods and Apparatus for Cleaning and Drying Wafers."

- 2) U.S. Patent 5,899,216 to Goudie et al., "Apparatus for Rinsing Wafers in the Context of a Combined Cleaning Rinsing and Drying System."

Sincerely,



Stephen B. Ackerman,
Reg. No. 37761



Form PTO-1449

INFORMATION DISCLOSURE CITATION
IN AN APPLICATION

(Use several sheets if necessary)

Doctor Number (Optional)

TSMC-02-1129

Appleton Number

10/666, 493

Accident

Engineering Department

Ring Date 09/19/03

Groups And Units

U. S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

OTHER DOCUMENTS (Including Author, Title, Date, Portion or Pages, Etc.)

EXAMINER	DATE CONSIDERED
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EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.